

**AMENDMENTS TO THE SPECIFICATION**

Please replace the paragraph bridging pages 14 and 15 of the Specification with the following new paragraph.

The N-side pattern electrode layer 14 is composed of, for example, a Ni/Ti/Au metal laminate film. The transparent insulation layer 15 is composed of, for example, SiO<sub>y</sub>, SiON, Al<sub>2</sub>O<sub>3</sub>, ZrO<sub>2</sub> or SiN<sub>z</sub>. Further, the highly reflective metal layer 17 is composed of, for example, a high reflectivity metal such as Al, Ag, Pd, In or Ti, and formation thereof is achieved, for example, by depositing any of these materials by a sputtering method or a vapor deposition method. The term "high reflectivity metal" herein means a metal material having a reflectivity which is higher than a reflectivity observed in an interface between the SiC substrate 11 and the N-side pattern electrode layer 14 in ohmic contact with the back surface 11b of the SiC substrate 11. The high reflectivity metal is preferably such that a ~~resistivity reflectivity~~ observed in an interface between the transparent insulation layer 15 and the high reflectivity metal is higher than a reflectivity observed in an interface between the surface of the SiC substrate and a brazing material in contact with the SiC substrate as shown in Fig. 6.

Please replace paragraph [0024] with the following new paragraph.

[0024] Fig. 2 is a bottom view illustrating an exemplary pattern of the N-side pattern electrode layer 14. In this example, the N-side pattern electrode layer 14 is a continuous line constituted by a plurality of electrode lines line segments 14a which are

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configured in a honeycomb pattern to be distributed on the entire back surface 11b of the SiC substrate 11. More specifically, the plurality of electrode ~~lines~~ line segments 14a define a large hexagonal pattern surrounding a center region of the SiC substrate 11 and a radial line pattern including ~~lines~~ line segments respectively extending radially from the vertices of the hexagonal pattern. The N-side pattern electrode layer 14 is not necessarily required to be configured in such a pattern, but may be configured, for example, in a lattice pattern.